REMARKS

Examiner W. Wright is thanked for the thorough examination and search of the subject

Patent Application. Claims 1-15 and 18-25 have been canceled and new Claims 26-33 have been added.

The making final of the restriction requirement is noted. Non-elected claims 1-15 and 18-25 are hereby canceled. A divisional application to the non-elected claims will be filed once the elected claims are found allowable.

All Claims are believed to be in condition for Allowance, and that is so requested.

Reconsideration of the rejection under 35 U.S.C. 103 of Claims 16 and 17 as being unpatentable over De Santis is requested in accordance with the following remarks.

The De Santis reference was referred to in the Specification. De Santis uses a wet scrubber in addition to a combustion process. See col. 5, lines 26-31. Applicants' invention does not require a combustion process; and in fact, specifically does not use a combustion process or "burn box" because of the danger if fire (see page 4 of the Specification). New Claim 30 claims the absence of a combustion process. De Santis's wet scrubbing process is also different from Applicants' process. De Santis applies a gas feed stream containing nitrogen, oxygen, and silane (col. 5, lines 17-19). This provides a source of oxygen for the reaction to form silicon dioxide. The scrubbing takes place within the aspiration section 11 and the orifice

CS-00-198

section 12 (col. 5, line 60 - col. 6, line 14). When the gas enters the separation housing 34, it has

already been scrubbed (col., 6, lines 21-24). While it is agreed that the silicon dioxide is

separated out of the spent scrubbing liquid in the separation chamber (col. 6, lines 34-42), this is

not the same process taught in Applicants' invention. In Applicants' invention, the scrubbing

takes place under the water within the water-filled chamber. On page 5 of the Specification, it is

taught that the silane gas enters the water-filled chamber under the water (see new claims 26, 27,

and 30). The reaction of the silane gas with oxygen takes place within the water. The oxygen is

dissolved in the water in the chamber. There is no teaching or suggestion in De Santis that the

scrubbing take place within the separation chamber 34. Scrubbing takes place within the flow of

scrubbing liquid. Applicants' invention does not require the extra expense and complexity of

the scrubbing liquid flow and jet pump of De Santis.

Reconsideration of the rejection under 35 U.S.C. 103 of Claims 16 and 17 as being

unpatentable over De Santis is requested in accordance with the remarks above.

Allowance of all Claims is requested.

It is requested that should Examiner Wright not find that the Claims are now Allowable

that the Examiner call the undersigned at 765 4530866 to overcome any problems preventing

allowance.

Respectfully submitted,

Rosemary L. S. Pike. Reg # 39,332

Roserrony ISRde

7